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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

NISHIMOTO et al

Serial No.: 08/897,839

Filed: July 21, 1997

For: STRESS-ADJUSTED INSULATING
FILM FORMING METHOD,
SEMICONDUCTOR DEVICE AND
METHOD OF MANUFACTURING THE
SAME



Group Art Unit: 2814

Examiner: K. Eaton

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97(c)

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

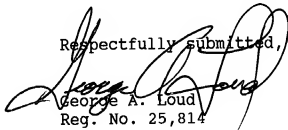
It is respectfully requested that the examiner consider and cite of record the three references cited in the European Search Report issued March 9, 1999 in connection with EPO Application 971127634-2203, believed to correspond to the captioned application. Copies of the European Search Report and the references cited therein are submitted herewith.

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CERTIFICATION

The undersigned hereby certifies that each item of information contained in this Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application no more than three (3) months prior to today's date.

Respectfully submitted,



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Reg. No. 25,814

Dated: May 4, 1999

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